

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of :
Jin-Sung KIM et al. :
Serial No.: [NEW] : Attn: Applications Branch
Filed: October 31, 2003 : Attorney Docket No.: SEC.1049
For: METHOD OF FORMING A POROUS MATERIAL LAYER IN A
SEMICONDUCTOR DEVICE

CLAIM OF PRIORITY

Honorable Assistant Commissioner for Patents and Trademarks,
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants, in the above-identified application, hereby claim the priority date
under the International Convention of the following Korean application:

Appln. No. 10-2002-0069262 filed November 8, 2002

as acknowledged in the Declaration of the subject application.

A certified copy of said application is being submitted herewith.

Respectfully submitted,

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Date: October 31, 2003